Amendment to the Claims

Claims 1-3: **(Withdrawn)**

4. **(Currently Amended)** An acoustic wave apparatus comprising:

a piezoelectric substrate mainly containing lithium tantalate;

an interdigital transducer including a conductor formed on said substrate; and

a reflector including a conductor formed on said substrate,

wherein a surface rotated in a range of 34° to 41° from a crystal Y axis around a crystal X axis of the lithium **tantalate** ~~tantalite~~ is set as a surface of said substrate, a standardized electrode thickness (h/λ) obtained by standardizing a thickness h of an electrode finger constituting at least a part of said reflector by a wavelength λ of a surface acoustic wave is set in a range of 0.01 to 0.05, and a duty ratio (w/p) of the electrode finger decided based on a width w and an arraying cycle p of the electrode finger is set to the value ranging from 0.6 to just below 1.0.

5. (Previously Amended) An acoustic wave apparatus comprising:

a piezoelectric substrate mainly containing lithium tantalate;

an interdigital transducer including a conductor formed on said substrate; and

a reflector including a conductor formed on said substrate,

wherein a surface rotated in a range of 35° to 42° from a crystal Y axis around a crystal X axis of the lithium tantalate is set as a surface of said substrate, a standardized electrode thickness (h/λ) obtained by standardizing a thickness h of an electrode finger constituting at least a part of said reflector by a wavelength λ of a surface acoustic wave is set in a range of 0.05 to 0.075, and a duty ratio (w/p) of the electrode finger decided based on a width w and an arraying cycle p of the electrode finger is set to the value ranging from 0.6 to just below 1.0.

6. (Previously Amended) An acoustic wave apparatus comprising:

a piezoelectric substrate mainly containing lithium tantalate;

an interdigital transducer including a conductor formed on said substrate; and

a reflector including a conductor formed on said substrate,

wherein a surface rotated in a range of 36° to 43° from a crystal Y axis around a crystal X axis of the lithium tantalate is set as a surface of said substrate, a standardized electrode thickness (h/λ) obtained by standardizing a thickness h of an electrode finger constituting at least a part of said reflector by a wavelength λ of a surface acoustic wave is set in a range of 0.075 to 0.1, and a duty ratio (w/p) of the electrode finger decided based on a width w and an arraying cycle p of the electrode finger is set to the value ranging from 0.6 to just below 1.0.

Claims 7-9: **(Withdrawn)**

10. **(Previously Amended)** An acoustic wave apparatus comprising:

a piezoelectric substrate mainly containing lithium tantalate;

an interdigital transducer including a conductor formed on said substrate; and

a reflector including a conductor formed on said substrate,

wherein a surface rotated in a range of 34° to 41° from a crystal Y axis around a crystal X axis of the lithium tantalate is set as a surface of said substrate, a standardized electrode thickness (h/λ) obtained by standardizing a thickness h of a part of an electrode finger constituting a part of said reflector by a wavelength λ of a surface acoustic wave is set in a range of 0.01 to 0.05, and a duty ratio (w/p) of a part of the electrode finger decided based on a width w and an arraying cycle p of a part of the electrode finger is set to the value ranging from 0.6 to just below 1.0.

11. **(Previously Amended)** An acoustic wave apparatus comprising:

a piezoelectric substrate mainly containing lithium tantalate;

an interdigital transducer including a conductor formed on said substrate; and

a reflector including a conductor formed on said substrate,

wherein a surface rotated in a range of 35° to 42° from a crystal Y axis around a crystal X axis of the lithium tantalate is set as a surface of said substrate, a standardized electrode thickness (h/λ) obtained by standardizing a thickness h of a part

of an electrode finger constituting a part of said reflector by a wavelength λ of a surface acoustic wave is set in a range of 0.05 to 0.075, and a duty ratio (w/p) of a part of the electrode finger decided based on a width w and an arranging cycle of a part of the electrode finger is set to the value ranging from 0.6 to just below 1.0.

12. **(Previously Amended)** An acoustic wave apparatus comprising:

a piezoelectric substrate mainly containing lithium tantalate;

an interdigital transducer including a conductor formed on said substrate; and

a reflector including a conductor formed on said substrate,

wherein a surface rotated in a range of 36° to 43° from a crystal Y axis around a crystal X axis of the lithium tantalate is set as a surface of said substrate, a standardized electrode thickness (h/λ) obtained by standardizing a thickness h of a part of an electrode finger constituting a part of said reflector by a wavelength λ of a surface acoustic wave is set in a range of 0.075 to 0.1, and a duty ratio (w/p) of a part of the electrode finger decided based on a width w and an arraying cycle p of a part of the electrode finger is set to the value ranging from 0.6 to just below 1.0.